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500.40120X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): T. OTSUBO, et al
Serial No.: 09/855,674
Filed: May 16, 2001
For: APPARATUS FOR MONITORING THICKNESS OF
DEPOSITED LAYER IN REACTOR AND DRY PROCESSING
METHOD
Group: 2877
Examiner: K. Brown

AMENDMENT

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

September 22, 2003

Sir:

In response to the Office Action dated June 19, 2003, the following amendments and remarks are respectfully submitted in connection with the above-identified application, as listed below and as set forth on the following pages:

Amendments to the Claims;

Remarks are included following the amendments; and

An Appendix including amended drawing figures is attached following the Remarks.

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